

Data Sheet- EddyCus® TF map 2530SR

P_T_2530_16



Highlights

- ▶ Contact-free imaging
- ▶ High resolution imaging (25 to 1,000,000 points)
- ▶ Integrity and defect imaging
- ▶ Mapping of encapsulated layers

Processes

- ▶ Deposition (PVD, evaporation, plating, CVD, ALD ...)
- ▶ Layer and material modification (implantation, doping, annealing)
- ▶ Layer removal (CMP, etching, scribing ...)

Applications

- ▶ Semiconductors
- ▶ Photovoltaics
- ▶ Touch panel sensors
- ▶ Displays and lighting
- ▶ Batteries, capacitors, fuel cells
- ▶ De-icing and heating
- ▶ Smart-glass and LowE
- ▶ WLP, PCB
- ▶ Packaging materials
- ▶ Antistatic

Materials

- ▶ Semiconductors (Si, SiC, GaAs ...)
- ▶ Metals
- ▶ Graphene, CNT, graphite
- ▶ Conductive oxides and nitrides
- ▶ Mesh and nanowire films
- ▶ Conductive inks, polymers (PEDOT)
- ▶ Other conductive films

SURAGUS GmbH
Maria-Reiche-Strasse 1
01109 Dresden
Germany

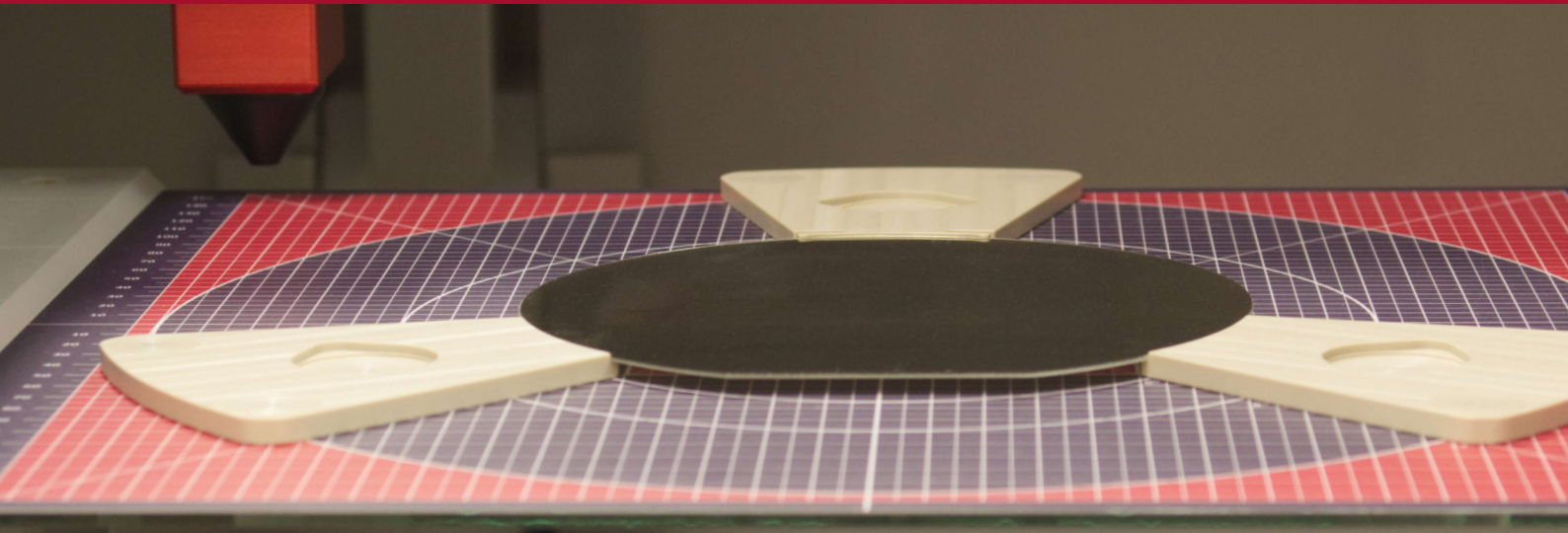
+49 351 32 111 520
info@suragus.com

www.suragus.com
www.sheet-resistance-testing.com
www.suragus.com/FAQ
www.suragus.com/EddyCusMap2530

Made and Engineered in Germany

Innovation Award by
Free State of Saxony 2013
1st Place





Measurement technology	Non-contact eddy current sensor
Substrates	Wafer, glass, foils etc.
Max. scanning area	12 inch / 300 mm x 300 mm (larger on request)
Edge effect correction / exclusion	2 – 10 mm (depending on size, measurement range and requirements)
Max. sample thickness / sensor gap	1 / 2 / 5 / 10 / 25 mm (defined by the thickest sample)
Sheet resistance ranges (up to 6 decades using one sensor)	Low 0.0001 – 1 Ohm / sq; 2 to 3 % accuracy Standard 1 – 1,000 Ohm / sq; 2 to 5 % accuracy High 1,000 – 10,000 Ohm / sq; 3 to 5 % accuracy
accuracy can be optimized over sheet resistance decade within a customer specified range	
Thickness measurement of metal films (e.g. Aluminum, Copper)	2 nm – 2 mm (in accordance with sheet resistance)
Scanning pitch (X and Y)	1 / 2.5 / 5 / 10 / 25 mm (other on request)
Measurement points per time	100 measurement points in 0.5 minutes 10,000 measurement points in 5 minutes 1,000,000 measurement points in 30 minutes
Scanning time	8 inch / 200 mm x 200 mm in 1.5 to 15 minutes (1 – 10 mm pitch) 12 inch / 300 mm x 300 mm in 2 to 15 minutes (2.5 – 25 mm pitch)
Device dimension (w /h /d) / weight	31.5 x 19.1 x 33.5 inch / 799 x 486 x 850 mm / 90 kg
Available features	Metal thickness imaging, anisotropy sheet resistance sensor

Software and Handling - Sheet Resistance Analyzer 2.0

